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L1	1	("6616759").PN.	USPAT	OR	OFF	2006/07/04 11:13
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L3	99	apc same model and wafer	USPAT	OR	OFF	2006/07/04 11:14
L4	1851	film adj stack	USPAT	OR	OFF	2006/07/04 11:14
L5	0	3 and 4	USPAT	OR	OFF	2006/07/04 11:14
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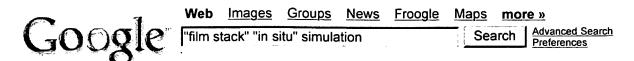
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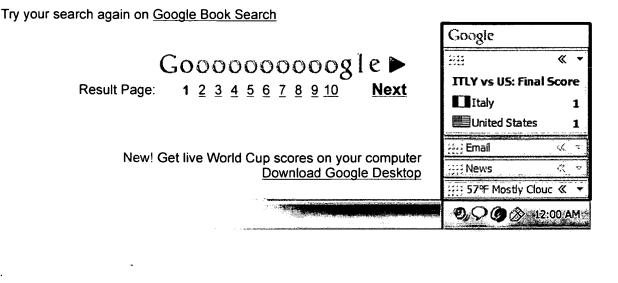
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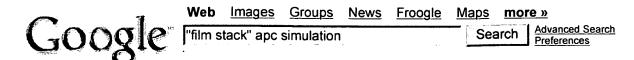
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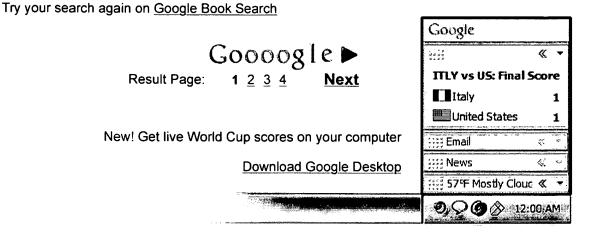
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